

Title (en)

METHOD FOR DEPOSITING SENSOR MATERIAL ON A SUBSTRATE

Title (de)

VERFAHREN ZUR ABLAGERUNG EINES SENSORMATERIALS AUF EINEM SUBSTRAT

Title (fr)

PROCÉDÉ DE DÉPÔT D'UN MATÉRIAU CONSTITUANT UN CAPTEUR SUR UN SUBSTRAT

Publication

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Application

EP 11720468 A 20110518

Priority

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- EP 2011058031 W 20110518

Abstract (en)

[origin: WO2011144652A2] A method for manufacturing a sensor, the method comprising: providing at least a sensor deposition area of a surface of a substrate with a predetermined microstructure; depositing a layer of sensor material on the microstructured sensor deposition area.

IPC 8 full level

G01N 21/77 (2006.01)

CPC (source: EP)

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Citation (search report)

See references of WO 2011144652A2

Citation (examination)

- ELENA MARTINES ET AL: "superhydrophobicity and superhydrophilicity of regular nanopatterns", NANO LETTERS, AMERICAN CHEMICAL SOCIETY, vol. 5, no. 10, 1 January 2005 (2005-01-01), pages 2097 - 2103, XP002454274, ISSN: 1530-6984, DOI: 10.1021/NL051435T
- J-G FAN ET AL: "Water contact angles of vertically aligned Si nanorod arrays; Water contact angles of vertically aligned Si nanorod arrays", NANOTECHNOLOGY, IOP, BRISTOL, GB, vol. 15, no. 5, 1 May 2004 (2004-05-01), pages 501 - 504, XP020067932, ISSN: 0957-4484, DOI: 10.1088/0957-4484/15/5/017

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